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# MAR 0 3 2005 IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| Application Serial No                  | 10/671,922                              |
|--|---|
| Confirmation No.                       | 8459                                    |
| Filing Date                            |   |
| Inventor                               | Garo J. Derdenan                        |
| Assignee                               | Micron Technology, Inc.                 |
| Group Art Unit                         | 2812                                    |
| Examiner                               | Lynne Ann Gurley                        |
| Attorney's Docket No                   | MI22-2296                               |
| Customer No                            |   |
| Title: Atomic Layer Deposition Methods | , and Methods of Forming Materials Over |
| Semiconductor Substrates               | •                                       |

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

# CERTIFICATE OF FACSIMILE TRANSMISSION UNDER 37 CFR § 1.8

I hereby certify that the following papers are being facsimile transmitted to the Patent and Trademark Office at (703) 872-9306 on the date shown below:

- 1. Certificate of Facsimile Transmission
- 2. Response to February 16, 2005 Office Action

| Dated: March 3, 2005 | By: A During                     |
|----------------------|----------------------------------|
| <u></u>              | Jennifer Gaines, Legal Assistant |
|                      | Telephone No. (509) 624-4276     |
|                      | Facsimile No. (509) 838-3424     |

#### **FEE DEFICIENCY**

Although it is believed that no fees are due, the Commissioner is hereby authorized to charge any fees under 37 C.F.R. 1.16 and 1.17 which may be required by this paper to Deposit Account No. 23-0925.

| Dated: | March 3, 2005 | By:            | 97  |  |
|--------|---------------|----------------|---|--|
|        |               | - <b>- 3</b> · | David G. Latwesen, Ph.D.<br>Reg. No. 38,533 |  |

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MAR 0 3 2005

### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| Application Serial No                   | 10/671,922                            |
|---|---------------------------------------|
| Confirmation No                         | 8459                                  |
| Filing Date                             | September 24, 2003                    |
| Inventor                                | Garo J. Derderian                     |
| Assignee                                | Micron Technology, Inc.               |
| Group Art Unit                          |                                       |
| Examiner                                |                                       |
| Attorney's Docket No                    |                                       |
| Customer No                             |                                       |
| Title: Atomic Layer Deposition Methods, | and Methods of Forming Materials Over |

## **RESPONSE TO FEBRUARY 16, 2005 OFFICE ACTION**

To:

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

From:

David G. Latwesen, Ph.D. (Tel. 509-624-4276; Fax 509-838-3424)

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### **AMENDMENTS**